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[10191/4116]  
REPLY UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
GROUP ART UNIT 2818

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : LAERMER et al.  
Serial No. : 10/524,610  
Filed : August 11, 2005  
For : LAYER SYSTEM HAVING A SILICON LAYER  
AND A PASSIVATION LAYER, METHOD FOR  
CREATING A PASSIVATION LAYER ON A  
SILICON LAYER AND ITS USE  
  
Group Art Unit : 2818  
  
Examiner : HO, Hoang Quan Tran  
Confirmation No. : 9981

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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Date: September 5, 2007

Signature: Chih Li

TRANSMITTAL

SIR:

Enclosed herewith for filing in the above-identified patent application is a Reply  
Under 37 C.F.R. § 1.116.

While no fee is believed due in connection with this paper, the Commissioner is  
hereby authorized to charge payment of any additional fees associated with this  
communication or credit any overpayment to the deposit account of **Kenyon & Kenyon  
LLP**, deposit account number **11-0600**.

Respectfully Submitted,  
KENYON & KENYON LLP

Dated: September 5, 2007

By: Gerard A. Messina

(Reg. No 35,952) *RV*

One Broadway  
New York, NY 10004  
(212) 425-7200

CUSTOMER NO. 26646

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[10191/4116]

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Signature: \_\_\_\_\_

*September 5, 2007*  
*Chili*

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Commissioner for Patents  
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**REPLY UNDER 37 C.F.R. § 1.116**

S I R:

This paper is filed in response to the Final Office Action dated June 15, 2007 in connection with the above-captioned application.

**Remarks** begin on page 2 of this paper.